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01/28/02

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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM 10058614	FILING DATE 01/28/2002	CLASS 324	SUBCLASS 751	GAU 2002	EXAMINER NGUYEN, VINH P.
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**APPLICANTS: Han Ligu; McCord Mark; 2829

**CONTINUING DATA VERIFIED:

THIS APPLN CLAIMS BENEFIT OF 60/341,348 12/17/2001

** FOREIGN APPLICATIONS VERIFIED:

DO NOT PUBLISH ☒

RESCIND ☐

Priority claimed

☐ yes ☐ no

35 USC 119 conditions met

☐ yes ☐ no

Verified and Acknowledged Examiner's Initials

ATTORNEY DOCKET NO.

KLA1P058

TITLE: Multiple electron beam inspection system using uniform focus and deflection

U.S. DEPT. OF COMM./PAT. & TM.-PT. 2 (3-01) (Rev. 12-24)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
		Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER		Primary Examiner PREPARED FOR ISSUE Application Examiner	
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